



John T. Moore

Title: Method of Forming Oxide Regions Over Semiconductor Substrates

Assignee: Micron Technology, Inc.

INFORMATION DISCLOSURE STATEMENT

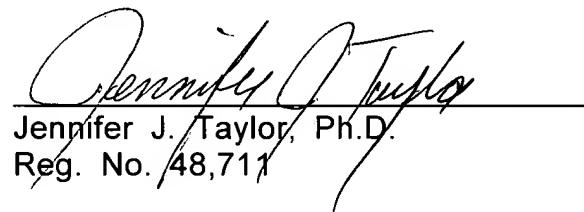
References – See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56. No admission is made regarding whether any of the submitted references is prior art. Copies of the references are attached.

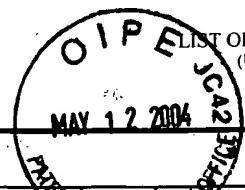
Respectfully submitted,

Dated: May 12, 2004

Attorney:



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Reg. No. 48,711

LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
John T. MooreFILING DATE
June 22, 2000GROUP
2813

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
AA	6,100,163	08-2000	Jang et al.			
AB	6,399,520 B1	06-2002	Kawakami et al.			
AC						
AD						
AE						
AF						
AG						
AH						
AI						
AJ						
AK						
AL						

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
AM							
AN							
AO							
AP							
AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR						
	AS						
	AT						

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.